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FORM PTO-1449 (Modified) LIST OF PATENTS AND PUBLICATIONS FOR APPLICANT'S INFORMATION DISCLOSURE STATEMENT (Use several sheets if necessary)

Sheet _1_ of _1_

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In the Application of Brennen et al.

Serial No.: 09/233,694

Filed: January 19, 1999

Art Unit: Unassigne

Examiner: Unassign

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Title: METHOD FOR PRODUCING HIGH-SURFACE AREA TEXTURING OF A SUBSTRATE, SUBSTRATES PREPARED THEREBY AND

MASKS FOR USE THEREIN

U.S. PATENT DOCUMENTS

Ref. Desig.	Document No.	Date	Name	Class	Sub Class	Filing Date
AA-1	4,478,677	Oct. 23, 1984	Chen et al.			
AB-1	4,490,210	Dec. 25, 1984	Chen et al.			
AC-1	4,490,211	Dec. 25, 1984	Chen et al.			
AD-1	4,923,772	May 8, 1990	Kirch et al.	430	5	
AE-1	5,500,071	Mar. 19, 1996	Kaltenbach et al.			
AF-1	5,571,410	Nov. 5, 1996	Swedberg et al.			
AG-1	5,658,413	Aug. 19, 1997	Kaltenbach et al.			
	Desig. AA-1 AB-1 AC-1 AD-1 AE-1 AF-1	Desig. AA-1 4,478,677 AB-1 4,490,210 AC-1 4,490,211 AD-1 4,923,772 AE-1 5,500,071 AF-1 5,571,410	Desig. Oct. 23, 1984 AA-1 4,478,677 Oct. 23, 1984 AB-1 4,490,210 Dec. 25, 1984 AC-1 4,490,211 Dec. 25, 1984 AD-1 4,923,772 May 8, 1990 AE-1 5,500,071 Mar. 19, 1996 AF-1 5,571,410 Nov. 5, 1996	Desig. Chen et al. AA-1 4,478,677 Oct. 23, 1984 Chen et al. AB-1 4,490,210 Dec. 25, 1984 Chen et al. AC-1 4,490,211 Dec. 25, 1984 Chen et al. AD-1 4,923,772 May 8, 1990 Kirch et al. AE-1 5,500,071 Mar. 19, 1996 Kaltenbach et al. AF-1 5,571,410 Nov. 5, 1996 Swedberg et al.	Desig. Chen et al. AA-1 4,478,677 Oct. 23, 1984 Chen et al. AB-1 4,490,210 Dec. 25, 1984 Chen et al. AC-1 4,490,211 Dec. 25, 1984 Chen et al. AD-1 4,923,772 May 8, 1990 Kirch et al. 430 AE-1 5,500,071 Mar. 19, 1996 Kaltenbach et al. AF-1 5,571,410 Nov. 5, 1996 Swedberg et al.	Desig. Class AA-1 4,478,677 Oct. 23, 1984 Chen et al. — AB-1 4,490,210 Dec. 25, 1984 Chen et al. — AC-1 4,490,211 Dec. 25, 1984 Chen et al. — AD-1 4,923,772 May 8, 1990 Kirch et al. 430 5 AE-1 5,500,071 Mar. 19, 1996 Kaltenbach et al. — — AF-1 5,571,410 Nov. 5, 1996 Swedberg et al. — —

FOREIGN PATENT DOCUMENTS

Exam. Init.	Ref. Desig.	Document No.	Publication Date	Country or Patent Office	Class	Sub Class	Translation YES NO
Cry	AH-1	7-241690	19 September 1995	Japan			X abstract only
Cuy	Al-1	7-80675	28 March 1995	Japan			х

OTHER DOCUMENTS (including Author, Title, Date, Pertinent Pages, etc.)

Exam.	nit. Ref. Desig.	Description
Cri	AJ-1	Krajnovich et al., "Formation of 'Intrinsic' Surface Defects During 248 mn Photoablation of Polyimide," <i>J. Appl Phys.</i> <u>73</u> :3001-3008 (1993)

Examiner:

Date Considered:

EXAMINER: Initial of citation considered whether or not the citation conforms with MPEP609. Draw a line through the citation if not in conformance and not considered. Include copy of this form with next communication to applicant.